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2812 #2



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Martin, Kirk  
Assignee: Nisene Technology Group  
Title: Method And Apparatus For Etching A Semiconductor Die  
Serial No.: 09/902,931 Filing Date: July 10, 2001  
Examiner: Unknown Group Art Unit: Unknown  
Docket No.: M-11706 US

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INFORMATION DISCLOSURE STATEMENT  
UNDER 37 CFR § 1.97(b)

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying form PTO-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

Citation of these documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;
2. a representation that a search has been made; or
3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

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Respectfully submitted,

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